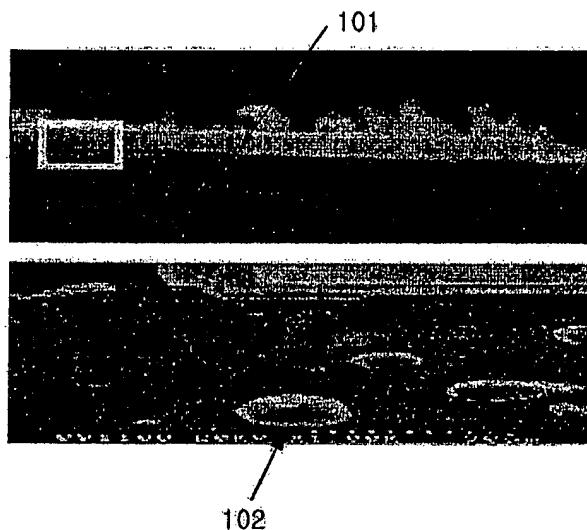




FIG. 1





Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800  
Title: STICKION-FREE MICROSTRUCTURE RELEASING METHOD FOR  
FABRICATING MEMS DEVICE  
1st Named Inventor: Won-Ick Jang  
Application No.: 09/753,065 Docket No.: 51876P232  
Sheet: 2 of 8

FIG. 2

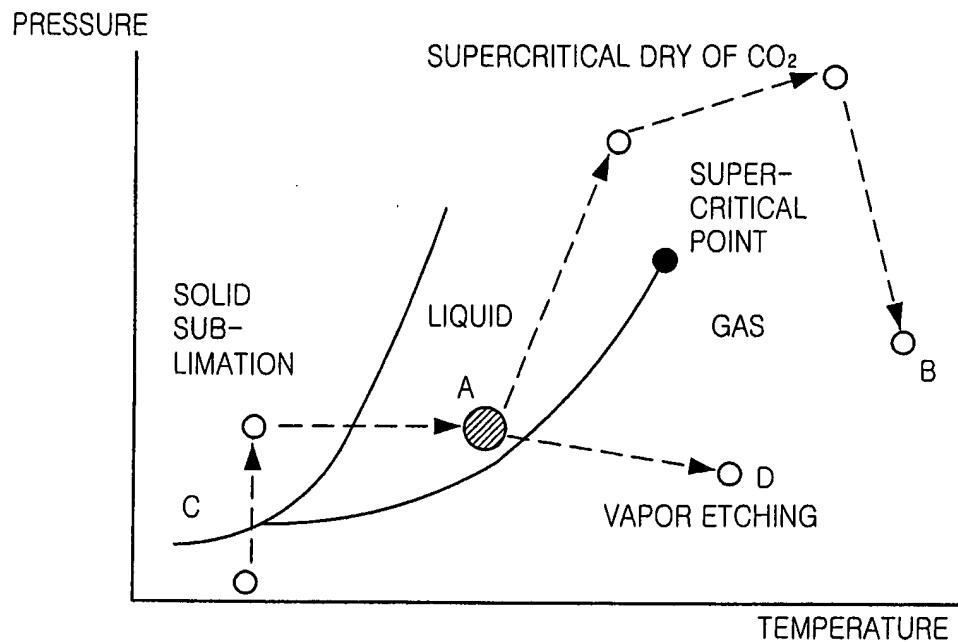
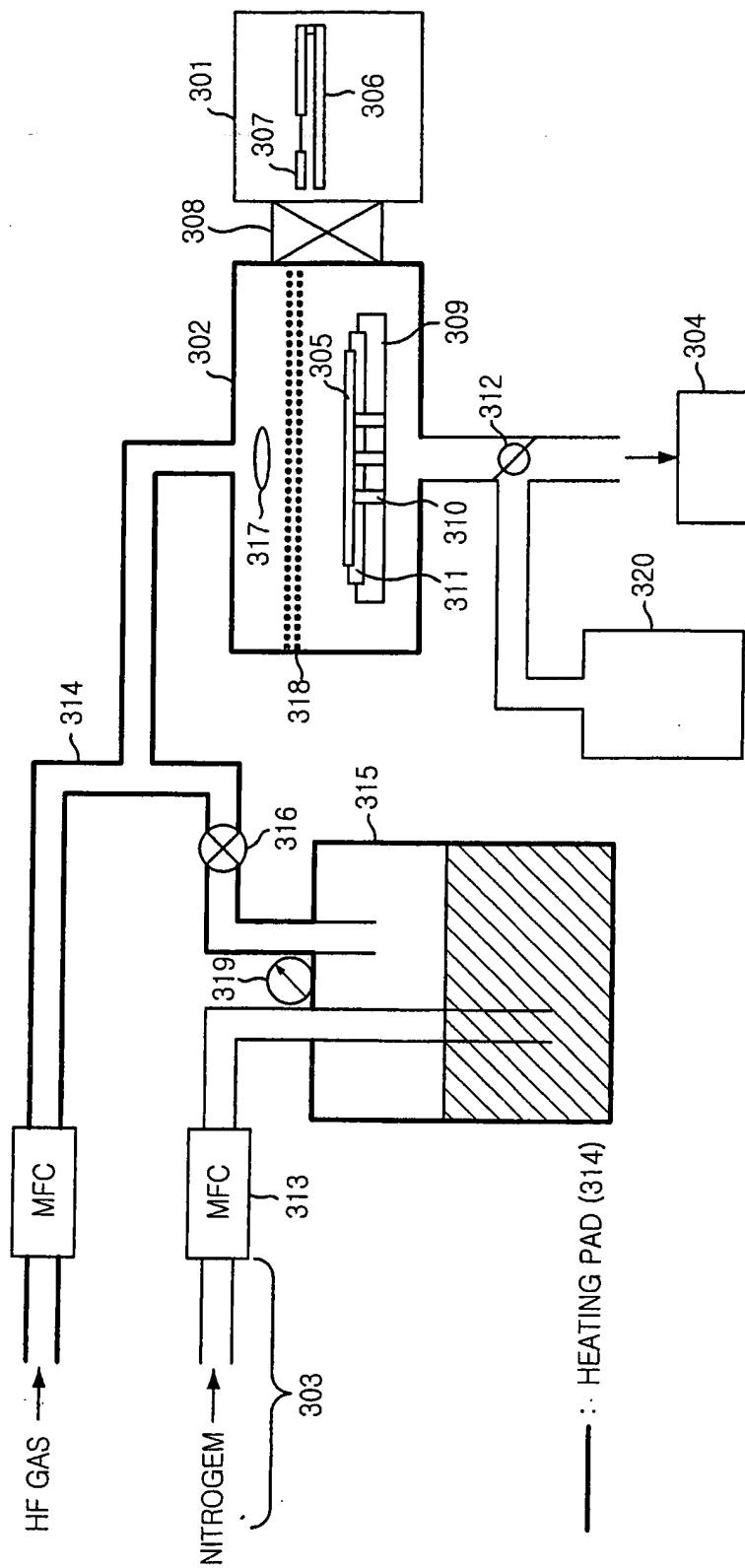


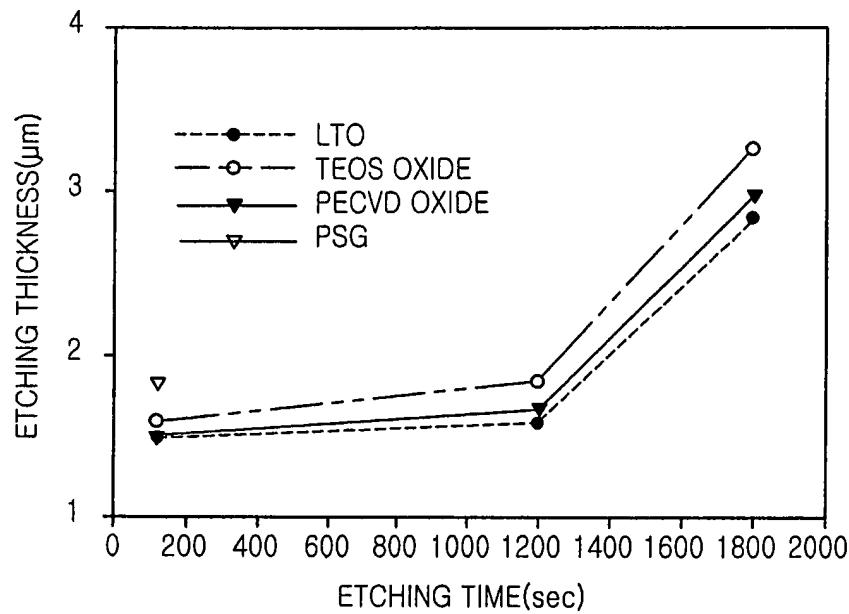
FIG. 3





Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800  
Title: STICKION-FREE MICROSTRUCTURE RELEASING METHOD FOR  
FABRICATING MEMS DEVICE  
1st Named Inventor: Won-Ick Jang  
Application No.: 09/753,065 Docket No.: 51876P232  
Sheet: 4 of 8

FIG. 4





Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800  
Title: STICKION-FREE MICROSTRUCTURE RELEASING METHOD FOR  
FABRICATING MEMS DEVICE  
1st Named Inventor: Won-Ick Jang  
Application No.: 09/753,065 Docket No.: 51876P232  
Sheet: 5 of 8

FIG. 5

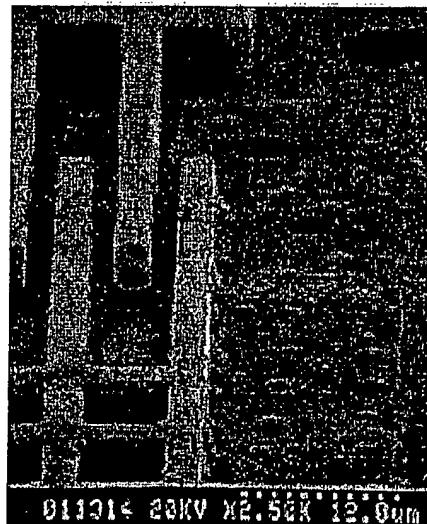
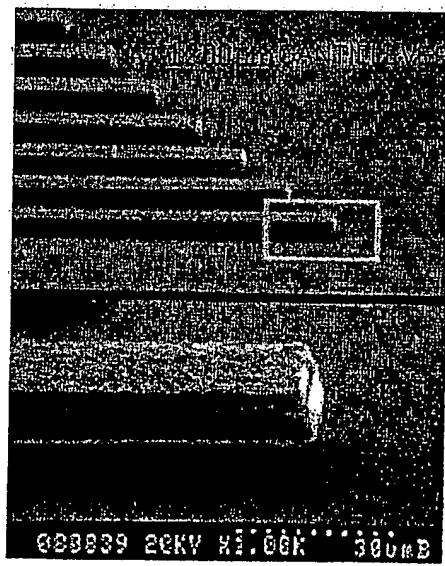


FIG. 6





Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800  
Title: STICKTION-FREE MICROSTRUCTURE RELEASING METHOD FOR  
FABRICATING MEMS DEVICE  
1st Named Inventor: Won-Ick Jang  
Application No.: 09/753,065 Docket No.: 51876P232  
Sheet: 6 of 8

FIG. 7

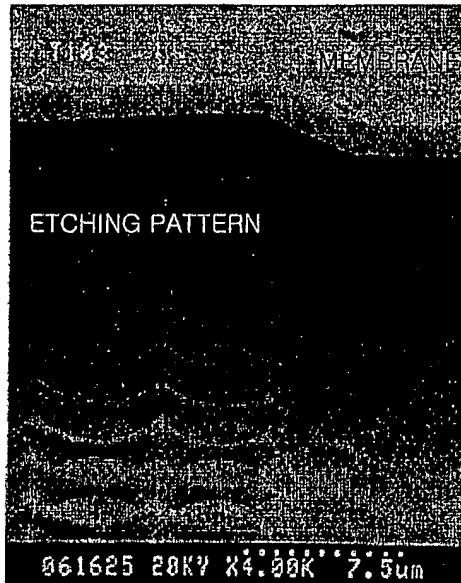


FIG. 8





Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800  
Title: STICKION-FREE MICROSTRUCTURE RELEASING METHOD FOR  
FABRICATING MEMS DEVICE  
1st Named Inventor: Won-Ick Jang  
Application No.: 09/753,065 Docket No.: 51876P232  
Sheet: 7 of 8

FIG. 9

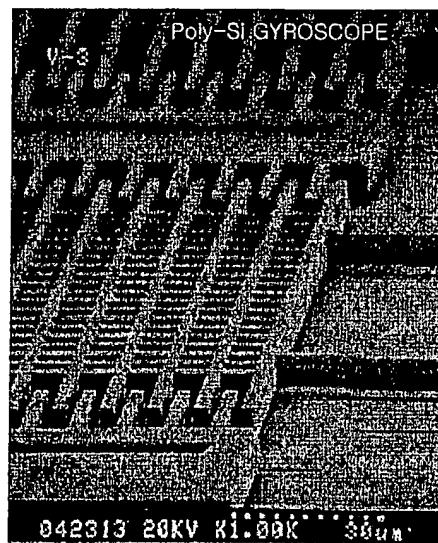
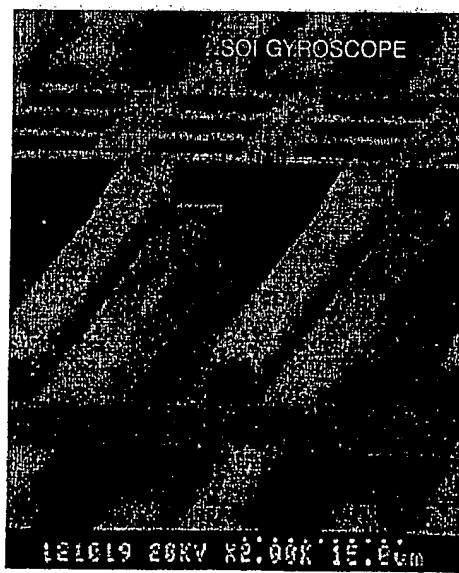


FIG. 10





Blakely, Sokoloff, Taylor & Zafman LLP (310) 207-3800  
Title: STICKTION-FREE MICROSTRUCTURE RELEASING METHOD FOR  
FABRICATING MEMS DEVICE  
1st Named Inventor: Won-Ick Jang  
Application No.: 09/753,065 Docket No.: 51876P232  
Sheet: 8 of 8

FIG. 11

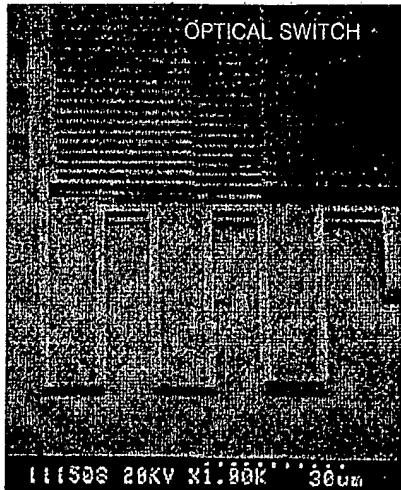


FIG. 12

